

# **IntelliSense Test Platform**

IntelliSense offers test and measurement services for various MEMS devices as well as related parameters during their fabrication process.

# 1. IntelliSense Measurement System for Pressure Sensor

- (1) Pressure regulator, Test chamber for high and low temperature, High accuracy voltage-stabilized source, Multimeter
- (2) Ability to measure sensor's nonlinearity, sensitivity, hysteresis loop, accuracy, temperature stability, etc..



**IntelliSense Measurement System for Pressure Sensor** 

#### 2. Characterization for MEMS Devices

#### (1) Laser Scanning Microscope

Used for the accurate measurement of surface topography, 3D structure and cross-section profile on semiconductor devices.



**Laser Scanning Microscope** 

### (2) Probe Stabilizer/ Semiconductor Parameters Test

Characterization of semiconductor devices. The Probe Stabilizer is mainly used for the electrical testing of devices, which is integrated with a pulse generator and switch selector. There is also a stress testing mode to ensure wafer reliability. It supports the measurement of capacitance in a quasi static. This stabilizer can help customers to have a reliable device quality, decrease the development time and the fabrication cost.



Probe Stabilizer/ Semiconductor Parameters testing instrument

## (3) Membrane Testing Instrument

Accurate measurement of the single- or double-layer thickness on the silicon wafer. Layer material can be silicon dioxide, silicon nitride, silicon oxynitride, polysilicon etc..

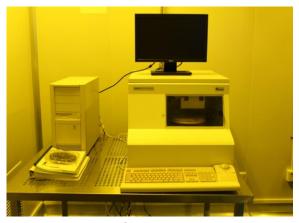


**Membrane Testing Instrument** 

# (4) Profilometer

For the measurement of 2D surface topography. Step range: 0-130 μm, scanning

range: 0-10mm.



**Profilometer** 

#### (5) Semiconductor Logical Analyzer

Mainly used for the measurement of the digital signal waveforms and also the generation of specific input pulses.



Semiconductor logical analyzer

### (6) Sheet Resistance Testing Instrument

For your convenient and quick measurement of the thin film sheet resistance by the four probe method.



**Resistance Testing Instrument**